APR 2 3 2004

Attorney Docket No. A-68359-1/RMA/JML Dorsey File No. 469113-41

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Gerard S. MALONEY et al.

Serial No.:

10/027,935

Filing Date:

December 21, 2003

For.

Apparatus and Method for Chemical-

Mechanical Polishing (CMP) Head Having Direct Pneumatic Wafer

Polishing Pressure

Examiner:

TBD

Group Art Unit: 3724

CERTIFICATE OF FAX TRANSMISSION

I hereby certify that this correspondence is being transmitted by facsimile transmission to fax # 703 872 9306 on April 23, 2004.

STATUS REQUEST

Technology Center 3700 Group Art Unit 3706 U.S. Patent Office Central Facsimile Number 703-872-9306

Sir.

Please provide the status of the above application as soon as possible:

Respectful# submitted, WHITNEY DORSEY

Jennifer M. Lane, Patent Agent, Reg. No. 51,916 R. Michael Ananian, Reg. No. 35,050

Attorney for Applicant

Four Embarcadero Center - Suite 3400 San Francisco, California 94111-4187

Tel.:

(415) 781-1989 (415) 398-3249

Fax: SF-1141558